

ABSTRACT

A method for purifying semiconductor waste gas comprises the step of: injecting hot air to a waste gas outlet of a semiconductor gas abatement system so that the hot air blows into semiconductor waste gas exhausted
5 from the waste gas outlet for catalyzing and decomposing harmful materials in the semiconductor waste gas. The hot air generates from a hot air generator and the hot air generator is installed in a head section of the semiconductor gas abatement system or directly on or at the outside of the semiconductor gas abatement system. Furthermore, the hot air generator is
10 connected to a hot air supply tube and the hot air is guided to the waste gas outlet in the tank. The hot air is generated from a hot air generator. Thereby, the harmful materials in the semiconductor waste gas can be cleaned completely.